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Docket No.: SON-1745  
(PATENT)

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7/15/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Seiichi Fukuda

Application No.: 09/512,336 Group Art Unit: 1765

Filed: February 24, 2000 Examiner: K. Chen

For: DRY ETCHING METHOD AND METHOD OF  
MANUFACTURING SEMICONDUCTOR  
APPARATUS

**AFTER FINAL RESPONSE AND REQUEST FOR RECONSIDERATION**

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the final Office Action dated June 9, 2003 (Paper No. 23), reconsideration of the final rejection of the claims of the above-identified U.S. patent application is requested in light of the following remarks.